WHAT IS CLAIMED IS:

1. A composition for forming a piezoelectric film containing a dispersoid obtained from a metallic compound, the composition comprising at least one of 1,8-diazabicyclo[5.4.0]-7-undecene, 1,5-diazabicyclo[4.3.0]non-5-ene, and 1,4-diazabicyclo[2.2.2]octane.

2. A piezoelectric film forming composition according to claim 1, wherein said metallic compound is an organometallic compound.

3. A piezoelectric film forming composition according to claim 1, wherein said at least one material is contained in an amount from 0.005 to 5.0 times of moles with respect to a number of moles of the total metal atoms in the piezoelectric film forming composition.

4. A piezoelectric film forming composition according to claim 1, comprising at least one of elements Pb, La, Zr and Ti as a constituent element.

5. A method for producing a piezoelectric element comprising:

a step of coating a substrate with a piezoelectric film forming composition containing a

dispersoid obtained from a metallic compound, and including at least one of 1,8-diazabicyclo[5,4,0]-7-undecene, 1,5-diazabicyclo[4.3.0]non-5-ene, and 1,4-diazabicyclo[2.2.2]octane to form a coated film;

a step of drying said coated film; and

a step of sintering said dried film to obtain a piezoelectric film.

6. A piezoelectric element including a piezoelectric film provided between a lower electrode and an upper electrode, wherein said piezoelectric film is prepared by a method according to claim 5.

7. An ink jet recording head comprising a pressure chamber communicating with an ink discharge port, a vibration plate provided corresponding to said pressure chamber, and a piezoelectric element according to claim 6, provided corresponding to said vibration plate, wherein ink in said pressure chamber is discharged from said ink discharge port by a volume change in said pressure chamber caused by said piezoelectric element.